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Front Matter: Volume 8616

, "Front Matter: Volume 8616," Proc. SPIE 8616, MOEMS and Miniaturized Systems XII, 861601 (13 March 2013); doi: 10.1117/12.2022906

SPIE.

Event: SPIE MOEMS-MEMS, 2013, San Francisco, California, United States

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MOEMS and Miniaturized Systems XII

Wibool Piyawattanametha
Yong-Hwa Park
Editors

4–6 February 2013
San Francisco, California, United States

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Published by
SPIE

Volume 8616

Proceedings of SPIE 0277-786X, V.8616

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

MOEMS and Miniaturized Systems XII, edited by Wibool Piyawattanametha,
Yong-Hwa Park, Proc. of SPIE Vol. 8616, 861601 · © 2013 SPIE
CCC code: 0277-786X/13/\$18 · doi: 10.1117/12.2022906

Proc. of SPIE Vol. 8616 861601-1

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Please use the following format to cite material from this book:

Author(s), "Title of Paper," in *MOEMS and Miniaturized Systems XII*, edited by Wibool Piyawattanametha, Yong-Hwa Park, Proceedings of SPIE Vol. 8616 (SPIE, Bellingham, WA, 2013) Article CID Number.

ISSN: 0277-786X

ISBN: 9780819493859

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445

SPIE.org

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Printed in the United States of America.

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